Porous Chuck

- Monolithic structure of porous and retainer
- Various available options
- Various available option
  The following material, pore size and porosity are available.
  - Material: \( \text{Al}_2\text{O}_3, \text{SiC} \)
  - Pore size: 5, 10, 30, 70\( \mu \text{m} \)
  - Porosity: 30~60%

- Design flexible
  Both square and circle design are available.
  Any inside tunnel pattern is available.

[Characteristics]

<table>
<thead>
<tr>
<th>Material</th>
<th>Al2O3</th>
<th>SiC</th>
</tr>
</thead>
<tbody>
<tr>
<td></td>
<td>Porous</td>
<td>Retainer</td>
</tr>
<tr>
<td>Specific gravity</td>
<td>2.5</td>
<td>3.9</td>
</tr>
<tr>
<td>Bending Strength ( MPa )</td>
<td>50</td>
<td>450</td>
</tr>
<tr>
<td>Young's modulus ( GPa )</td>
<td>55</td>
<td>390</td>
</tr>
<tr>
<td>CTE ( /℃ )</td>
<td>(7.4 \times 10^{-6})</td>
<td>(7.3 \times 10^{-6})</td>
</tr>
<tr>
<td>Thermal Conductivity ( W / m·K )</td>
<td>—</td>
<td>30</td>
</tr>
<tr>
<td>Volume Resistivity ( Ω·cm )</td>
<td>(10^{12})</td>
<td>(&gt;10^{14})</td>
</tr>
</tbody>
</table>

[Application]

- Fixture of grinding Si Wafer
  ( Dicing saw, Grinder, Polisher )
- Glass substrate carrier for LCD
- Fixture for various test equipment
- Fixing film sheet or metal substrate

[Example]

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This product specification and the catalog value are the references, and we may change of it without notice.

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